



## Supporting Information

for

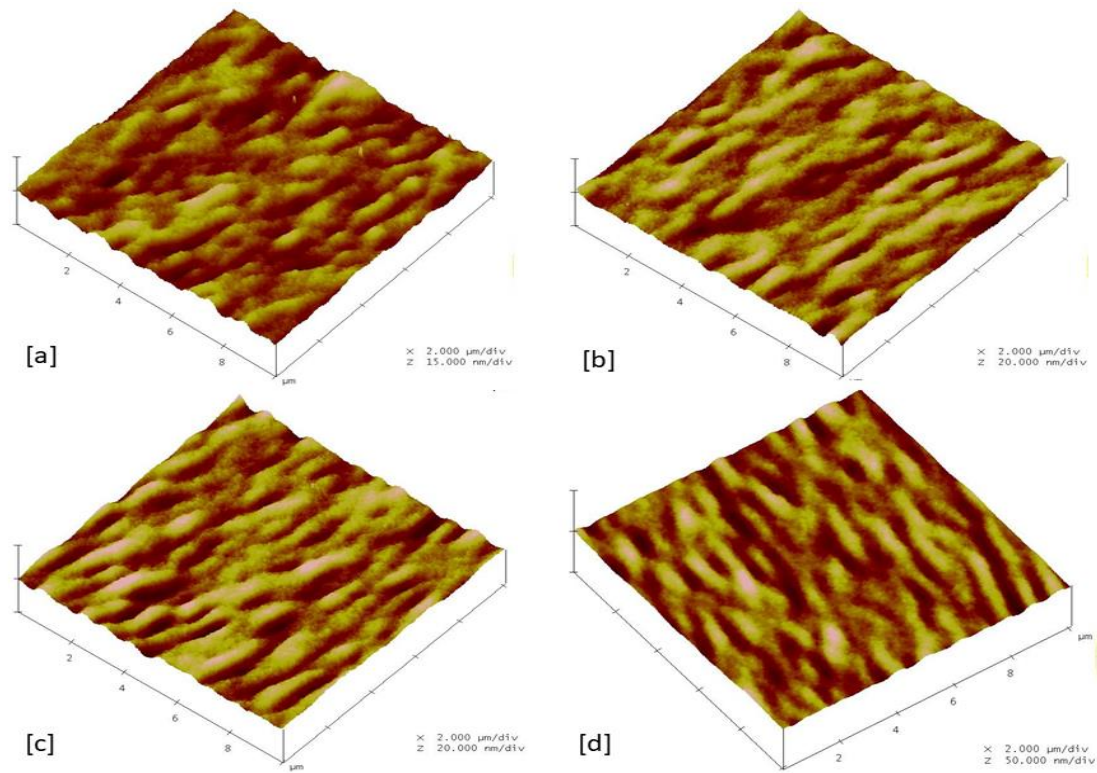
### **Investigating ripple pattern formation and damage profiles in Si and Ge induced by 100 keV Ar<sup>+</sup> ion beam: a comparative study**

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## Supplementary files

1. Si samples after irradiation at  $10 \times 10 \mu\text{m}^2$



2. Ge samples after irradiation at  $10 \times 10 \mu\text{m}^2$

